

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Shuji HAHAKURA, et al.

Title: METHOD OF PRODUCING
OXIDE SUPERCONDUCTING
FILM

Appl. No.: 10/511,268

International 04/17/2003

Filing Date:

371(c) Date: 10/20/2004

Examiner: Unknown

Art Unit: 1751

Confirmation 6578

Number:

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR §1.56

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Submitted herewith on Form PTO/SB/08 is a listing of documents known to Applicants in order to comply with Applicants' duty of disclosure pursuant to 37 CFR §1.56.

A copy of each non-U.S. patent document and each non-patent document is being submitted to comply with the provisions of 37 CFR §1.97 and §1.98.

The submission of any document herewith, which is not a statutory bar, is not intended as an admission that such document constitutes prior art against the claims of the present application or that such document is considered material to patentability as defined in 37 CFR §1.56(b). Applicants do not waive any rights to take any action which would be

appropriate to antedate or otherwise remove as a competent reference any document which is determined to be a *prima facie* art reference against the claims of the present application.

TIMING OF THE DISCLOSURE

The listed documents are being submitted in compliance with 37 CFR §1.97(b), before the mailing date of the first Office Action on the merits.

RELEVANCE OF EACH DOCUMENT

Any document listed on the attached PTO/SB/08 was cited as being relevant during the prosecution of the corresponding European application. A copy of the European Search Report is attached setting forth the portion of each document considered relevant by the examiner.

All of the documents are in English.

Applicants respectfully request that each listed document be considered by the Examiner and be made of record in the present application and that an initialed copy of Form PTO/SB/08 be returned in accordance with MPEP §609.

Although Applicant believes that no fee is required for this Request, the Commissioner is hereby authorized to charge any additional fees which may be required for this Request to Deposit Account No. 19-0741.

Respectfully submitted,

Date July 18, 2007

By

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<p>Substitute for form 1449/PTO</p> <p>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</p> <p>Date Submitted: July 18, 2007</p> <p>(use as many sheets as necessary)</p>				<p><i>Complete if Known</i></p>	
Sheet	1	of	1	Application Number	10/511,268
				Filing Date	10/20/2004
				First Named Inventor	Shuji HAHAKURA
				Art Unit	1751
				Examiner Name	Unknown
				Attorney Docket Number	040256-0135

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Documents	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ Number ⁴ Kind Code ⁵ (if known)				

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ⁶
	A2	DAM B ET AL: "The Transition from 2D-nucleation to spiral growth in pulsed laser deposited $\text{YBa}_2\text{Cu}_3\text{O}_7$ -delta films" PHYSICA C, North-Holland Publishing, Amsterdam, NL, vol. 305, no. 1-2, September 1998 (1998-09), pages 1-10, XP004142507, ISSN: 0921-4534	
	A3	NORTON M.G. ET AL.: "On the Optimization Of The Laser Ablation Process For The Deposition Of $\text{YBa}_2\text{Cu}_3\text{O}_7$ -Thin Films" PHYSICA C, North-Holland Publishing, Amsterdam, NL, vol. 172, no. 1/2, December 1, 1990 (1990-12-01), pages 47-56, XP000243732, ISSN: 0921-4534	
	A4	COTELL C.M. ET AL: "Microstructural Development Of Thin Films Grown By Pulsed Laser Deposition" MATERIALS SCIENCE AND ENGINEERING B, ELSEVIER SEQUOIA, LAUSANNE, CH, vol. 32, no. 3, July 1, 1995 (1995-07-01), pages 221-230, XP002297626, ISSN: 0921-5107	
	A5	FLTYN S.R. ET AL: "Pulsed Laser Deposition Of Thick $\text{YBa}_2\text{Cu}_3\text{O}_7$ -Films With $J_c>1 \text{ MA/cm}^2$ " APPLIED PHYSICS LETTERS, AIP, AMERICAN, vol. 63, no. 13, September 27, 1993 (1993-09-27), pages 1848-1850, XP000397802, ISSN: 0003-6951	

Examiner Signature _____ Date Considered _____

***EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. 1 Applicant's unique citation designation number (optional). 2 See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. 3 Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). 4 For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. 5 Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. 6 Applicant is to place a check mark here if English language Translation is attached. This collection of information is required by 37 CFR 1.97 and 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.